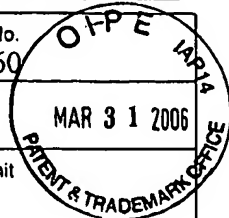


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| Information Disclosure Statement by Applicant (Use several sheets if necessary) | | Applicant Peter J. de Groot | |
| | | Filing Date September 9, 2003 | Group Art Unit 2877 |

(37 CFR §1.98(b))



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Substitute Form PTO-1449
(Modified)U.S. Department of Commerce
Patent and Trademark OfficeAttorney's Docket No.
09712-332001Application No.
10/659,060**Information Disclosure Statement
by Applicant**

(Use several sheets if necessary)

Applicant
Peter J. de GrootFiling Date
September 9, 2003Group Art Unit
2877**U.S. Patent Documents**

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